

Resolution and Texture Analysis

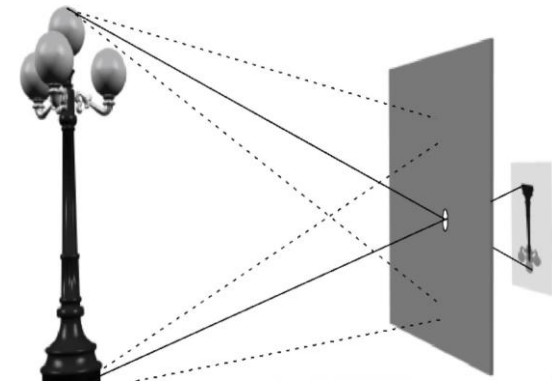
Navid Asadi

Physical Inspection and Attacks on ElectronicS (PHIKS)

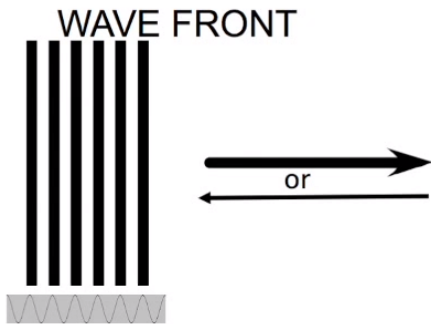
Resolution

- Why light does not provide infinite magnification
 - Light travels in straight line!
- Pin hole camera
 - If hole is bigger the image will be fuzzier
 - If hole is very small image gets blurry
 - Light is diffracted at the hole
- Light wave can travel in planar or spherical
 - Light is made of infinite small objects called Huygens wavelet

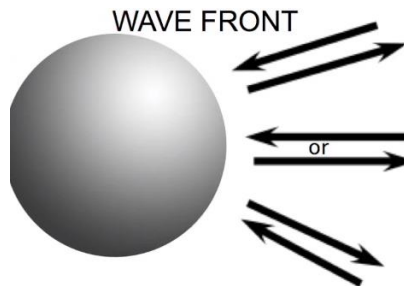
Pin hole camera



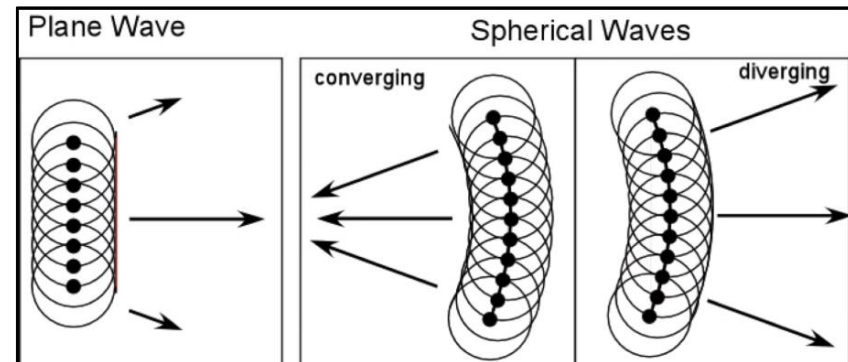
Planar wave



Spherical wave

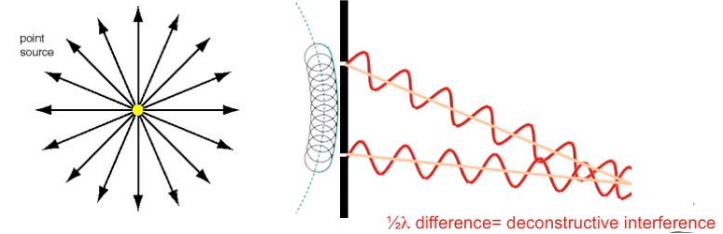
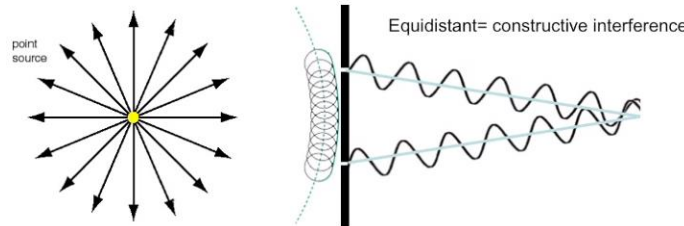
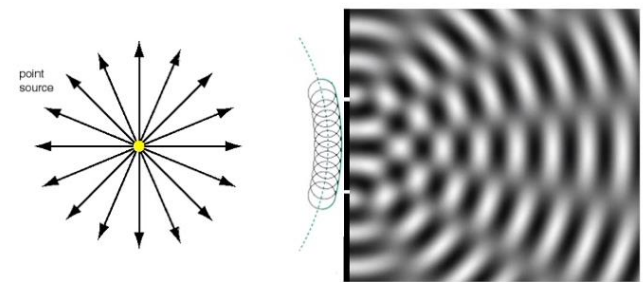
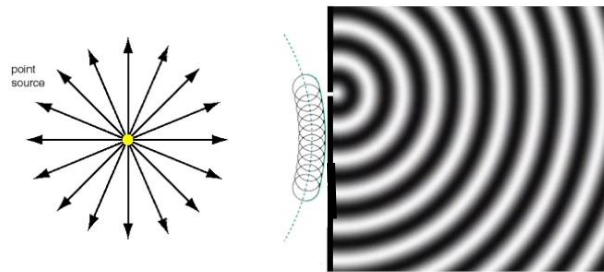
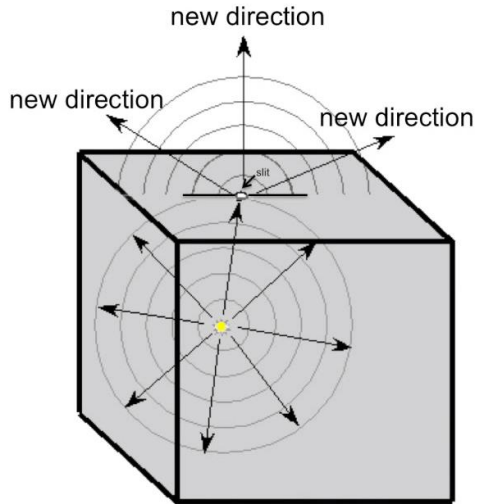


Peak and valley

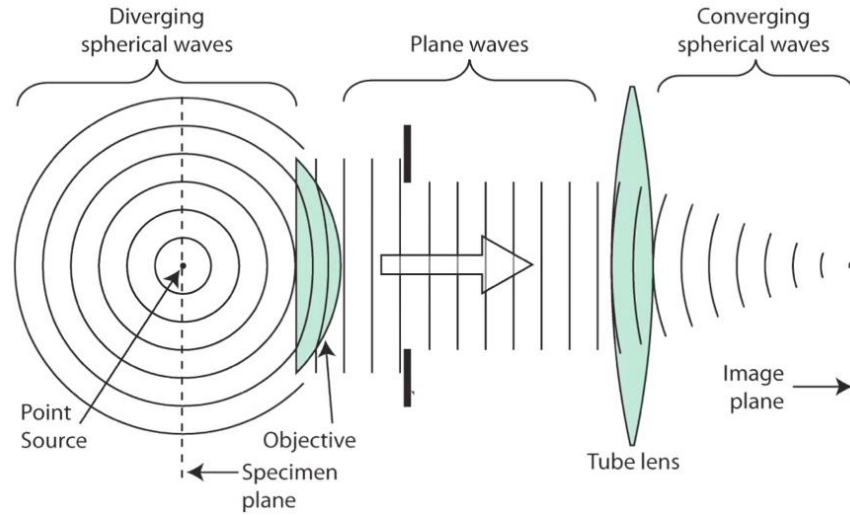


Light Diffraction

- Light in Wave form

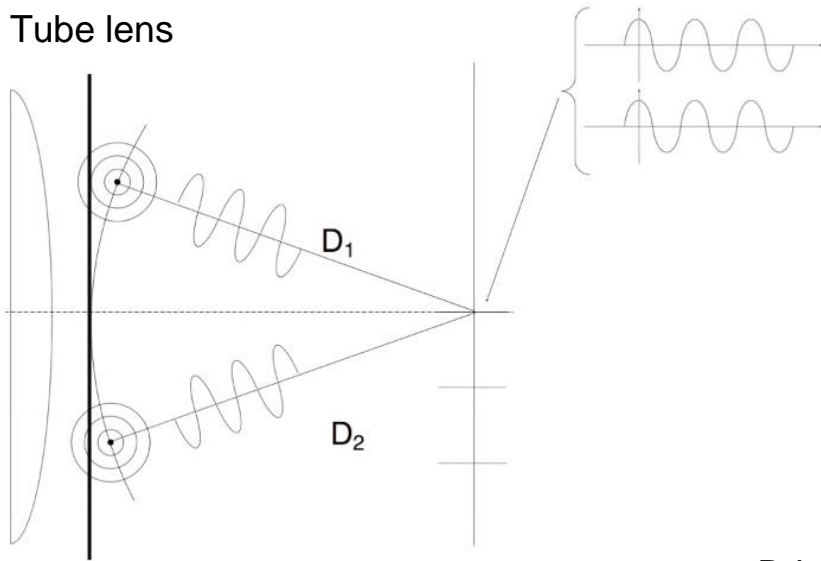


Optics of Microscope



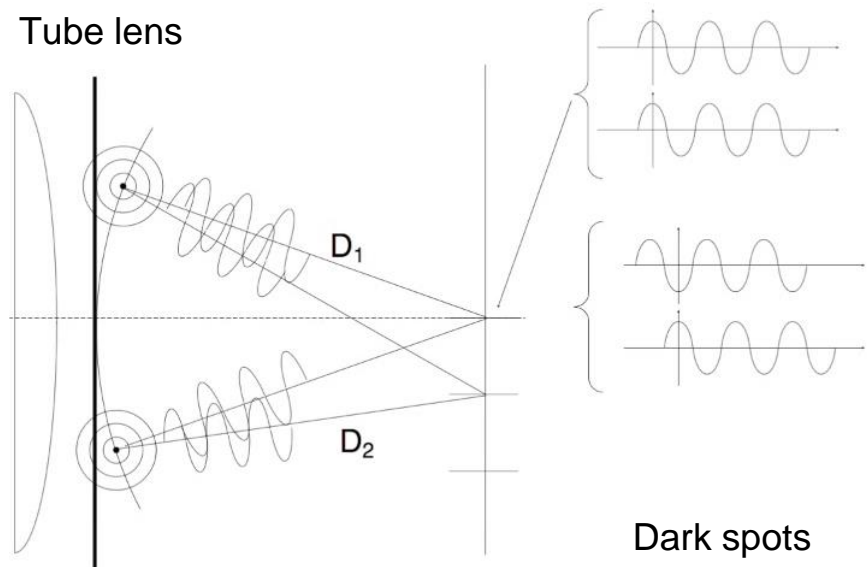
What is the distribution of light in this point
Point Spread Function

Tube lens



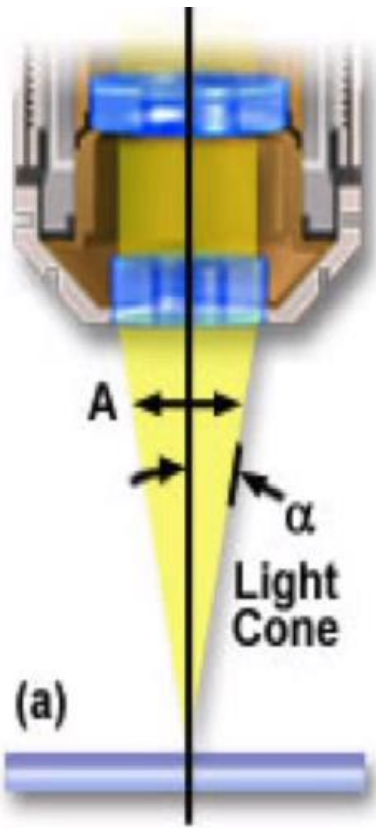
Bright spots

Tube lens

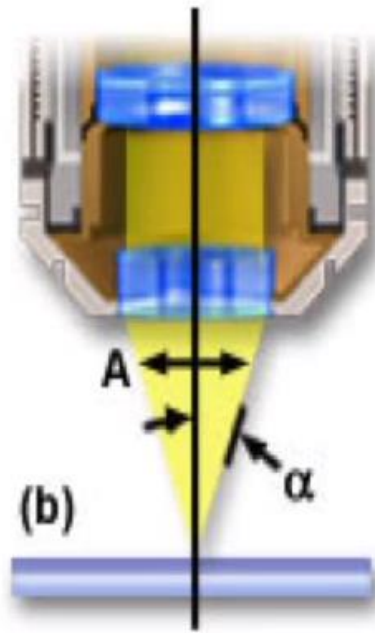


Dark spots

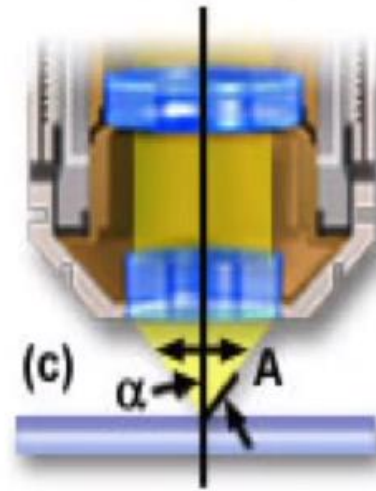
Numerical Aperture



Low NA



Medium NA



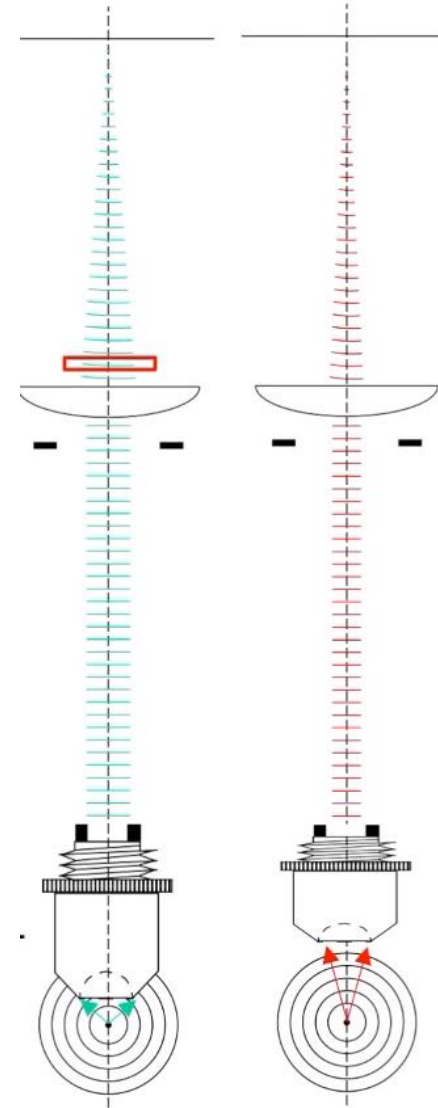
High NA

$$NA = n \cdot \sin(\alpha)$$

(a) $\alpha = 7^\circ$ NA = 0.12

(b) $\alpha = 20^\circ$ NA = 0.34

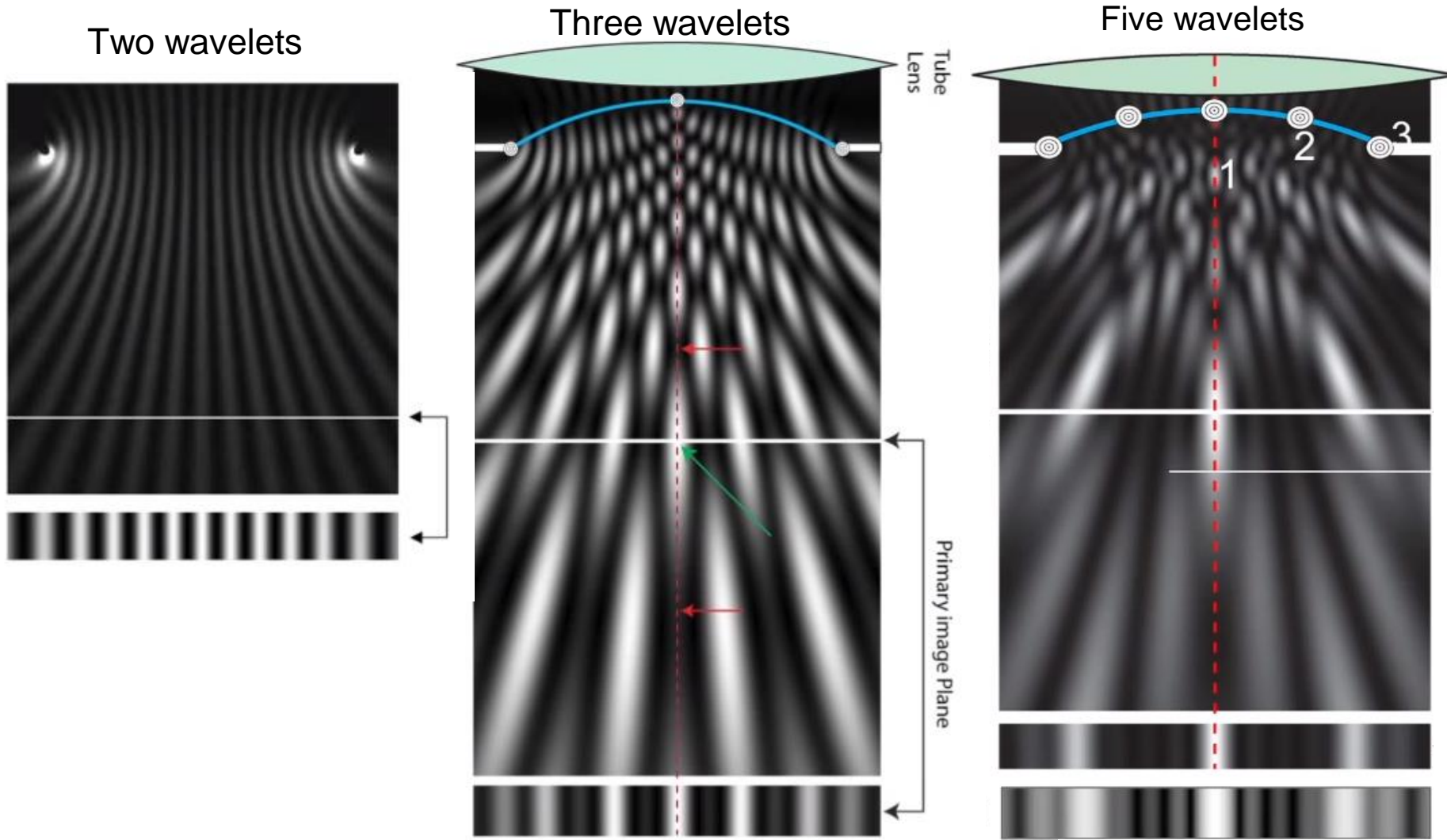
(c) $\alpha = 60^\circ$ NA = 0.87



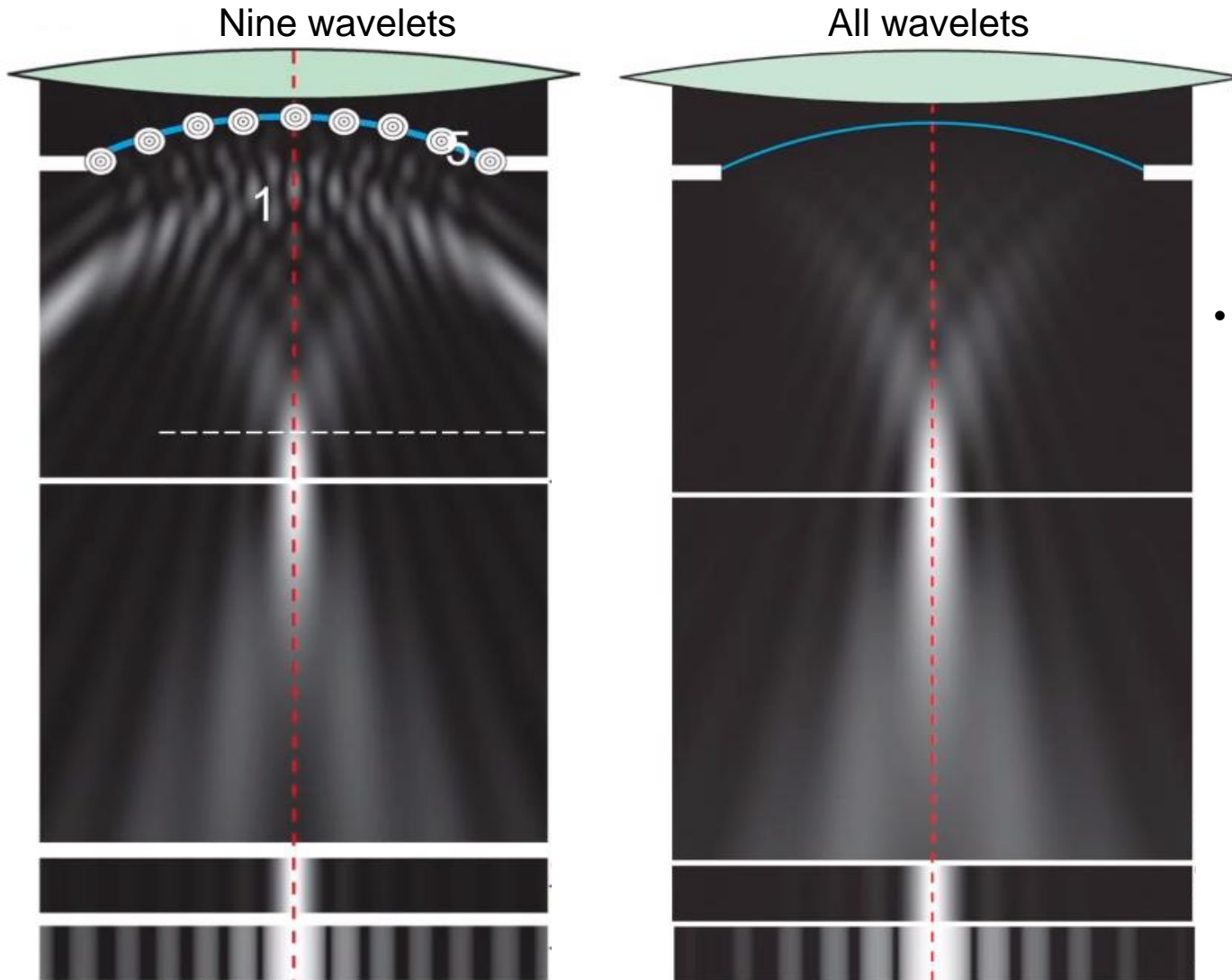
n: index of refraction

α : angle between vertical line and the most extreme light angle collected by lens

Effect of Wavelets



Effect of Wavelets

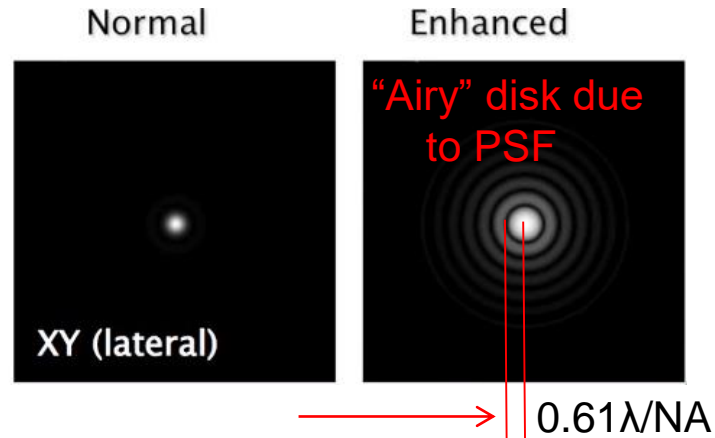


Point Spread Function (PSF)

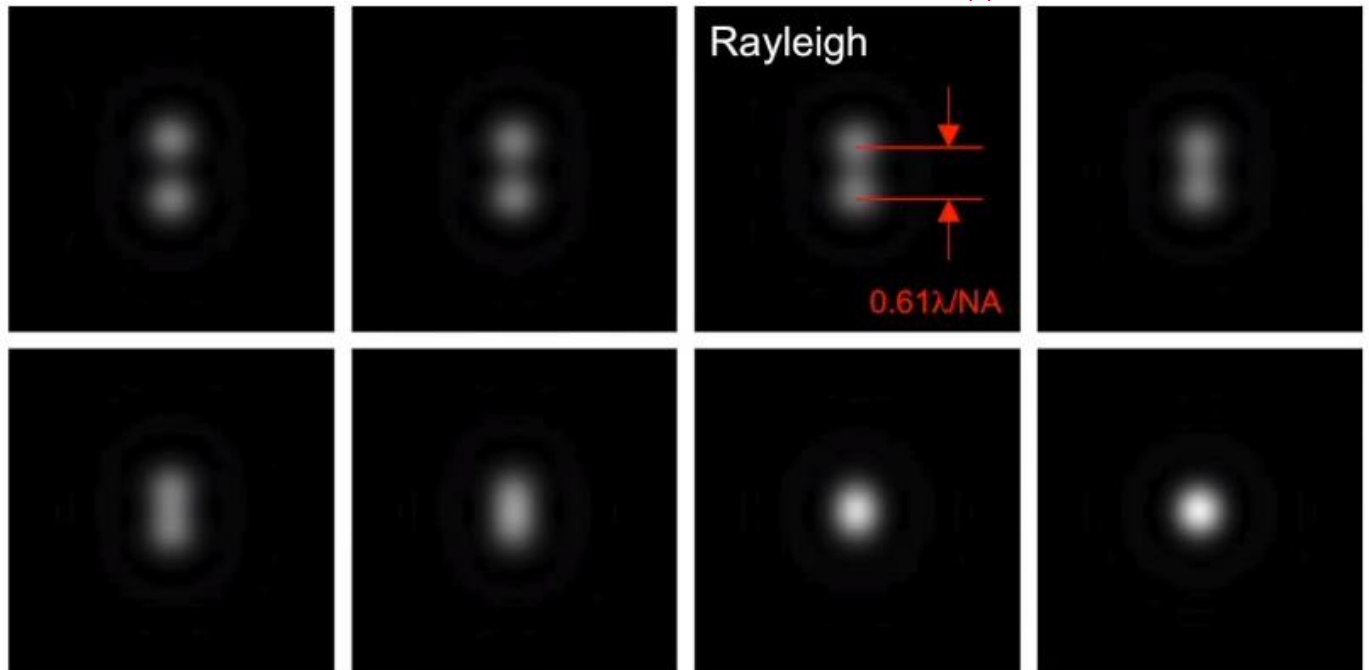
- Size of the image is related to the side wavelets and that is why NA is important

Resolving

- Looking down on the xy plane
- PSF has center Airy disks
- PSF has a series of concentric rings

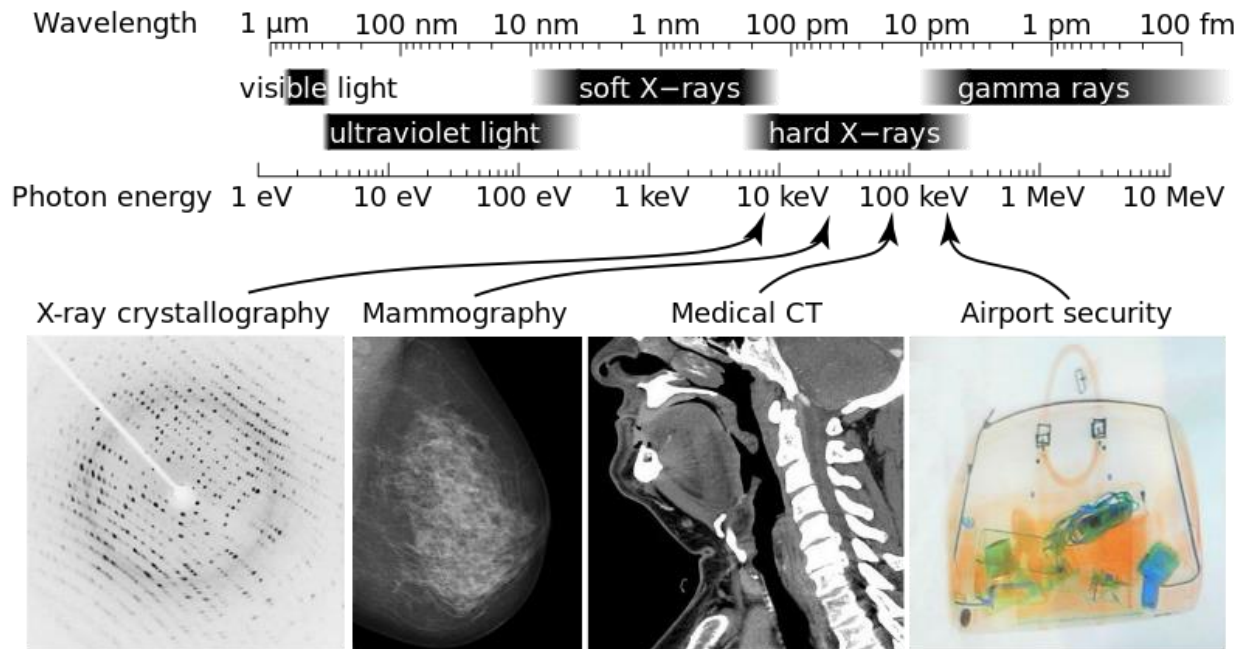
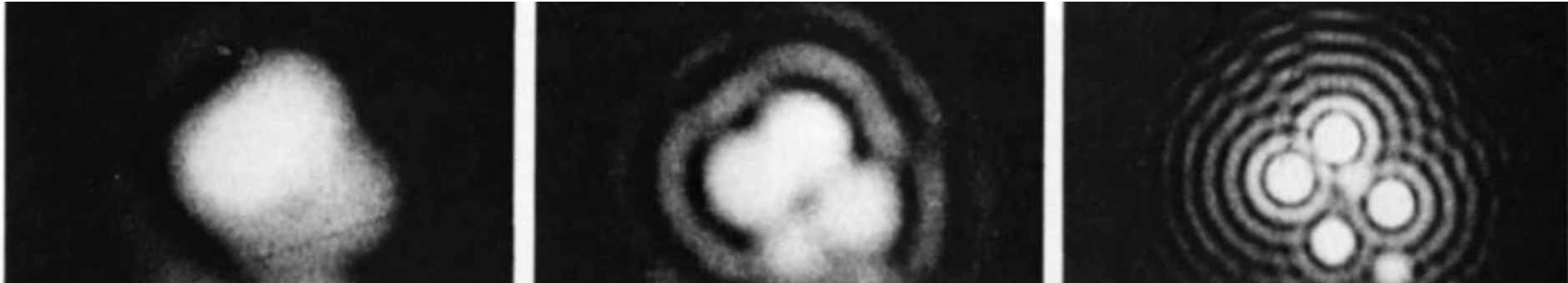


- There is no rule to define resolution but a generally accepted criterion of Rayleigh mostly used by microscopists.
- The center of an object is right at the first dark circle of other object

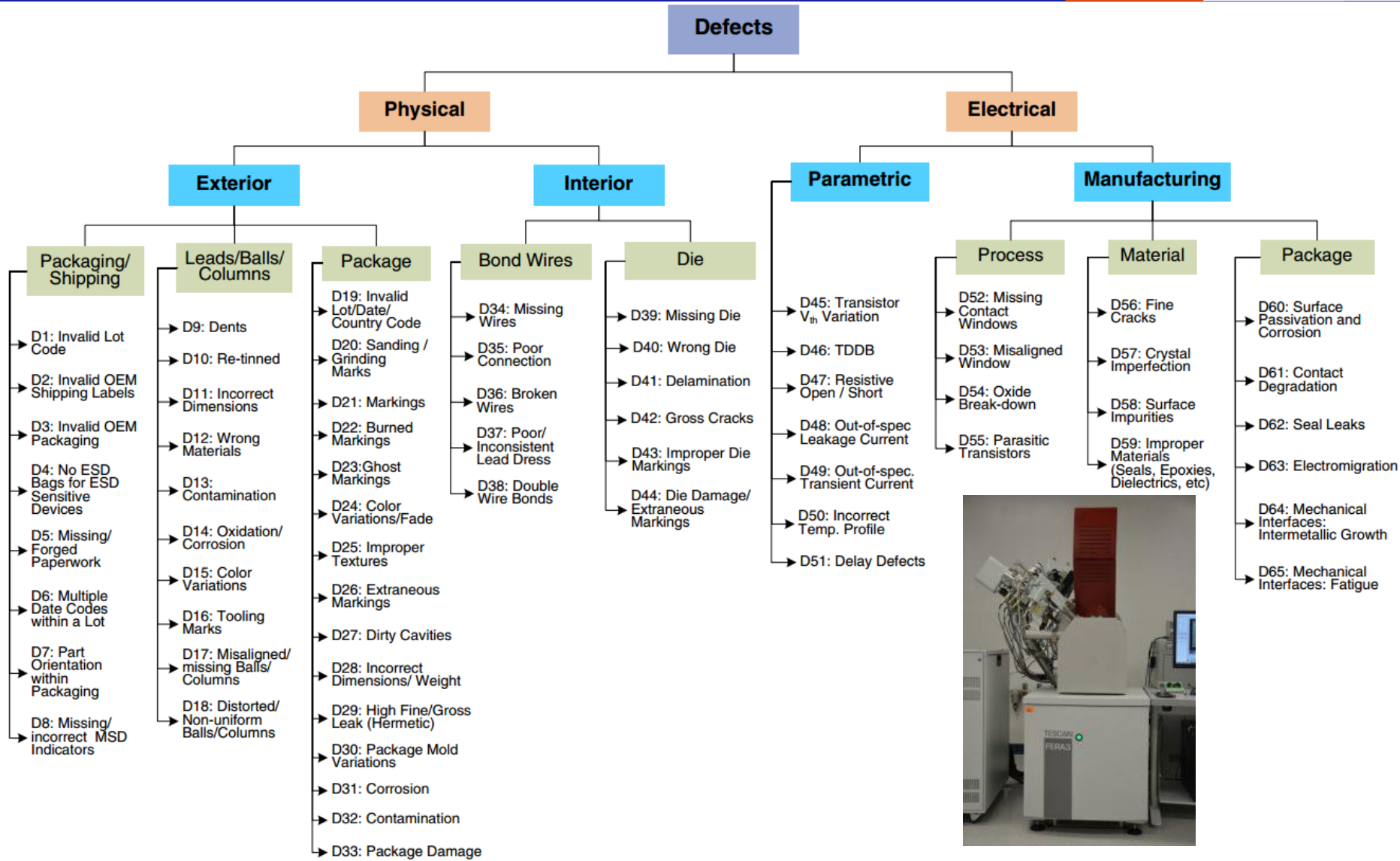


NA and Wavelength

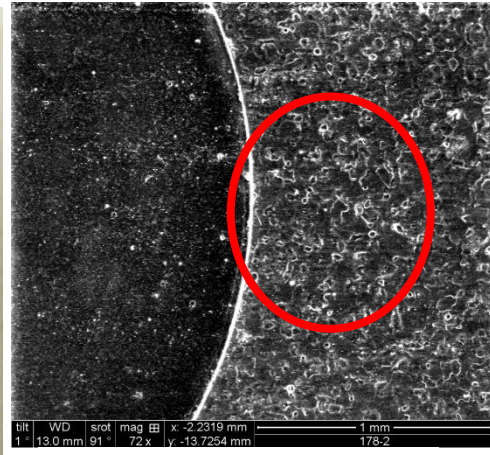
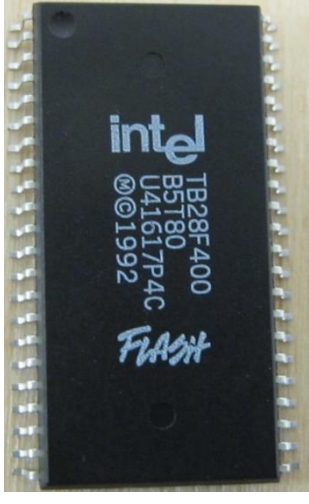
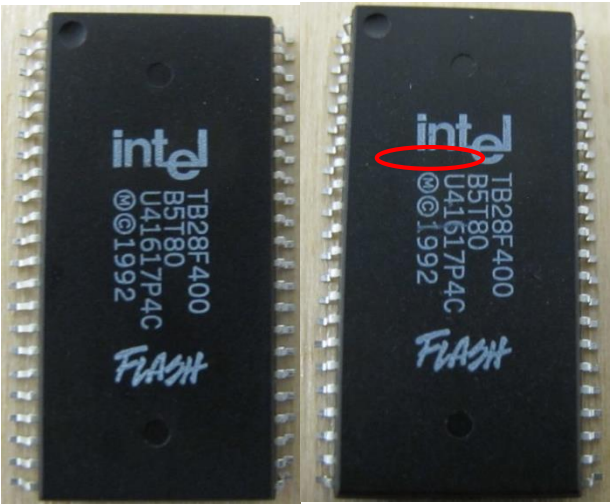
- Same magnification and different NA



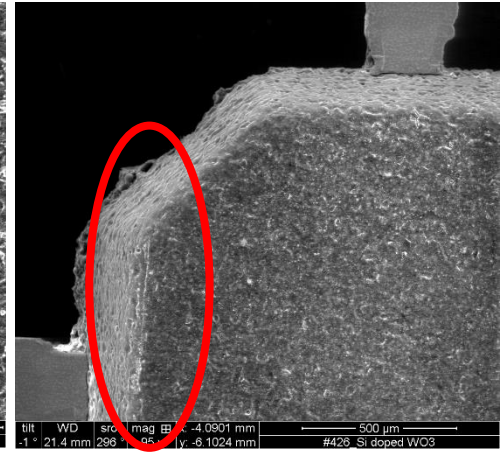
Taxonomy of Defects



SEM Imaging

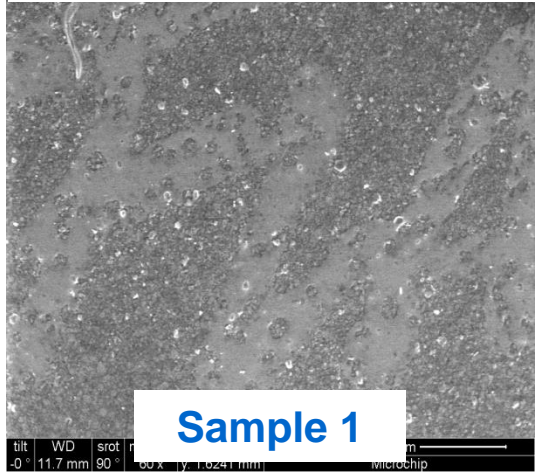


Polishing marks on smoothed top surface

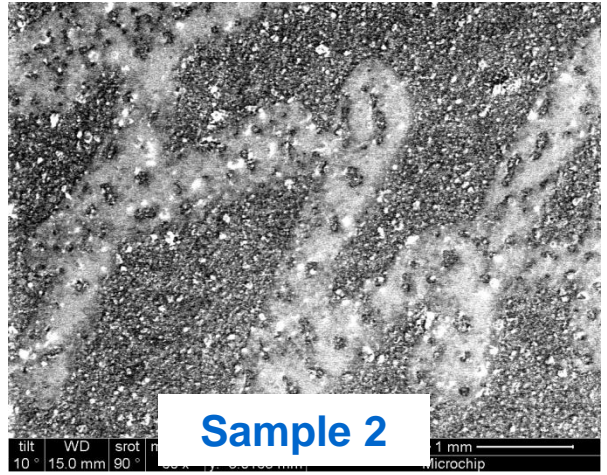


Improper Texture

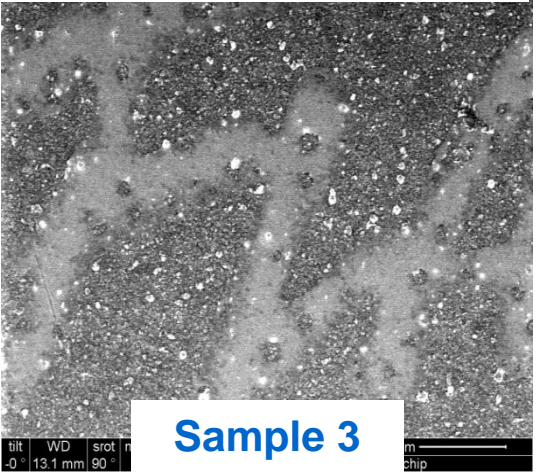
Texture Variation from one sample to the other



Sample 1



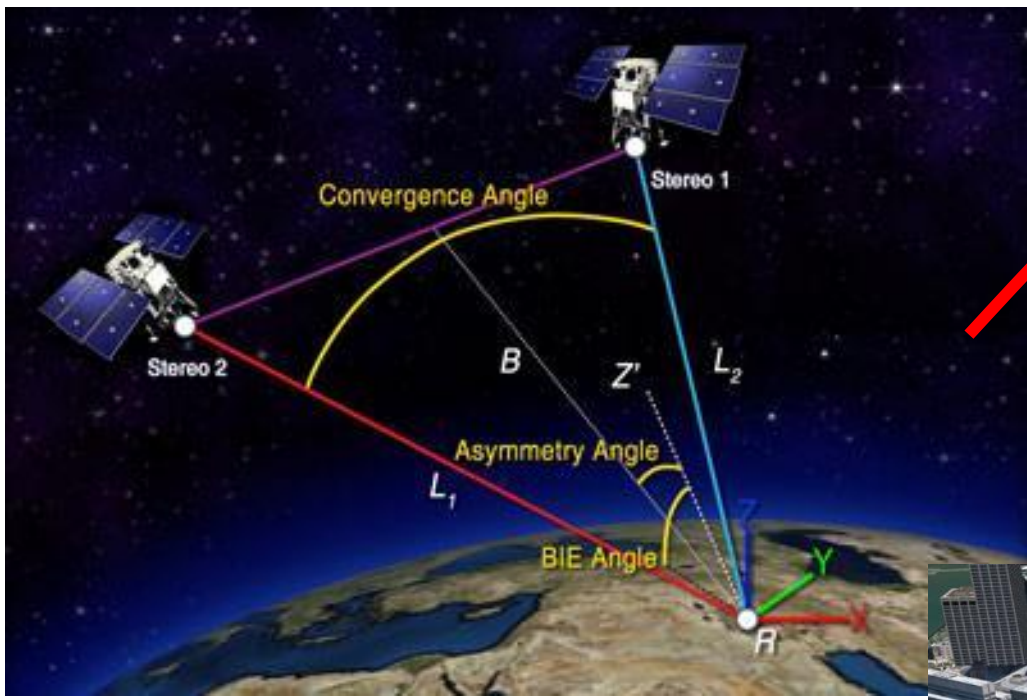
Sample 2



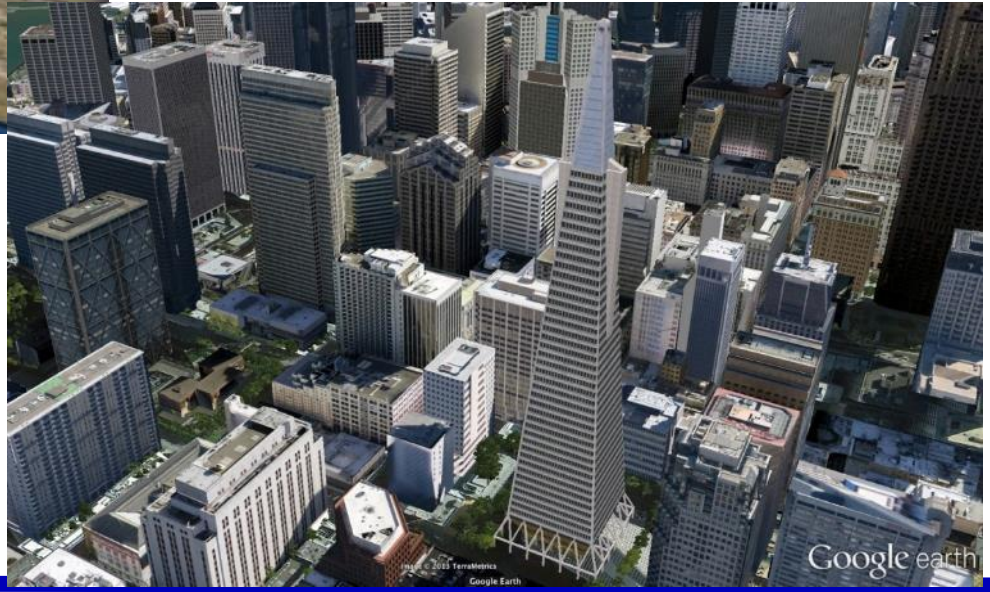
Sample 3

3D SEM Based Stereo-photogrammetry

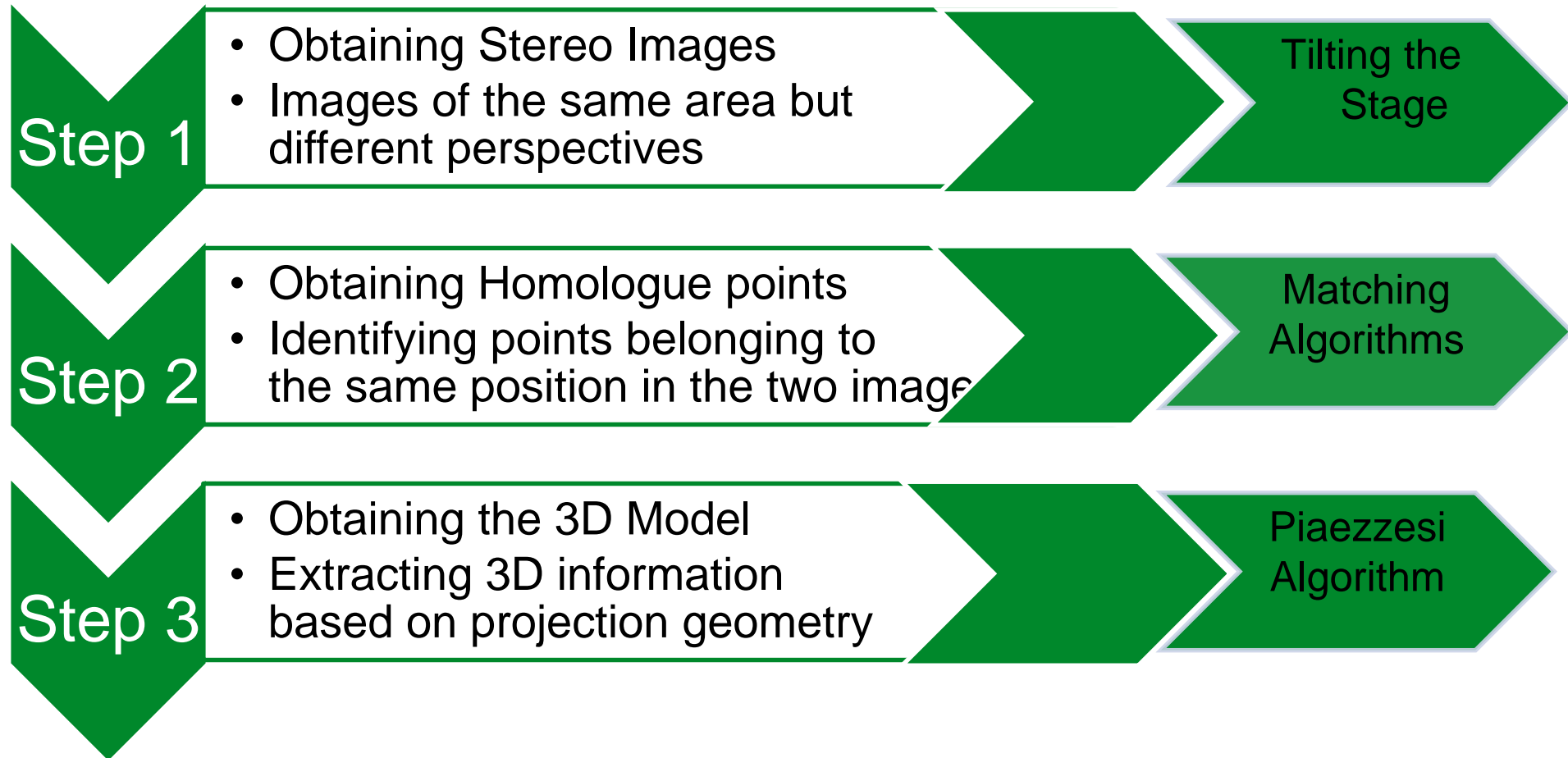
What is Stereo-photogrammetry?



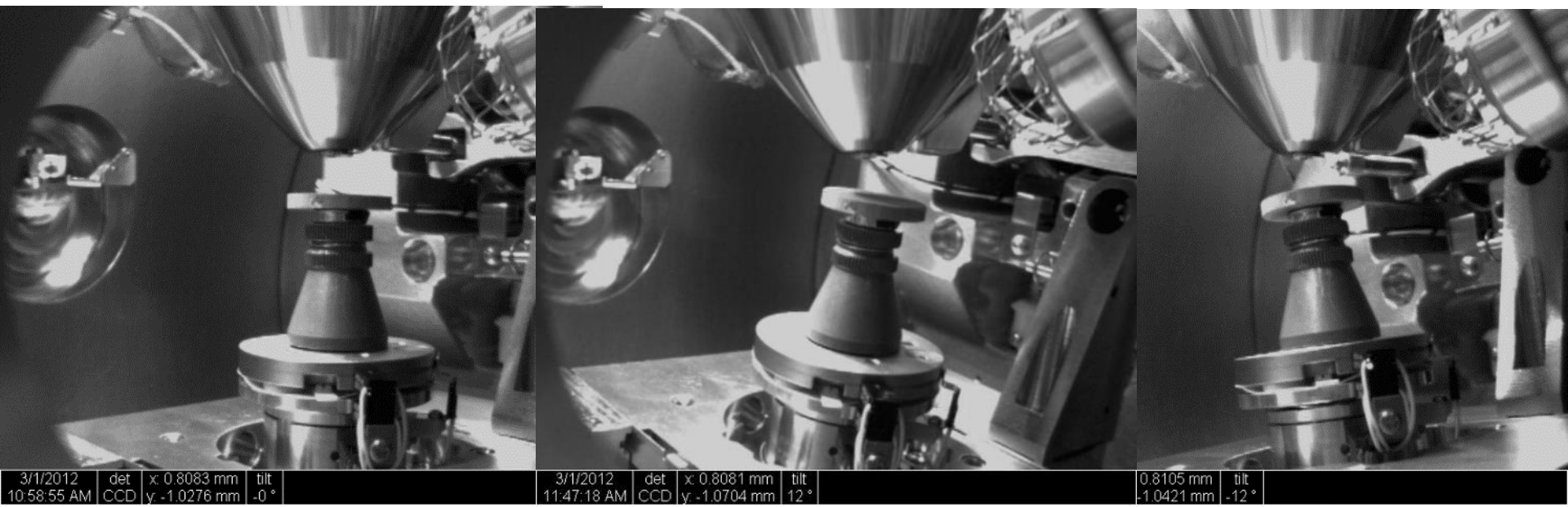
By Taking 2D images of the same Location at different perspective one can reconstruct the 3D image



3D SEM Based Stereo-photogrammetry

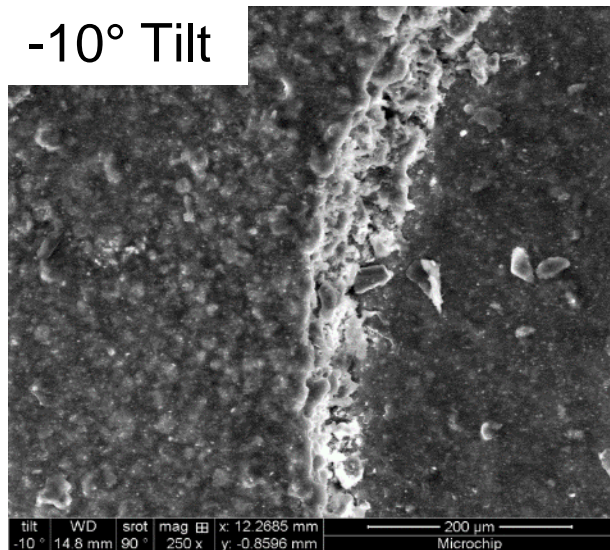


3D SEM Based Stereo-photogrammetry

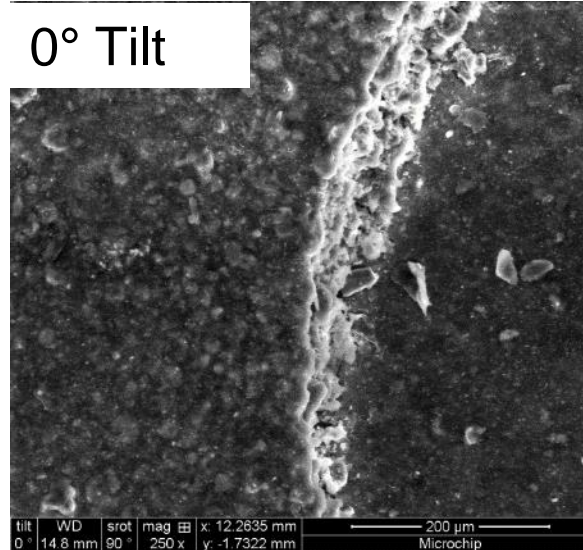


SEM- Stereo photogrammetry on a Dimple

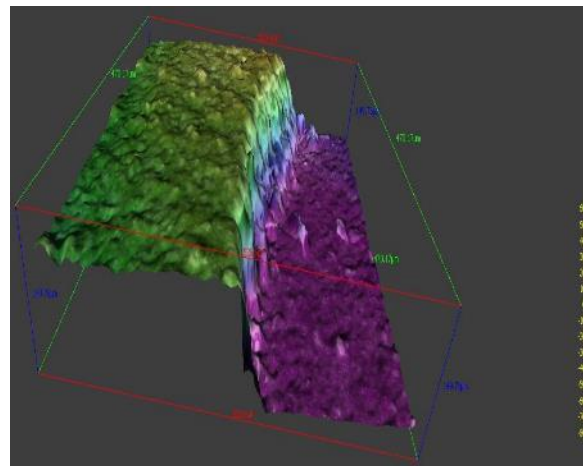
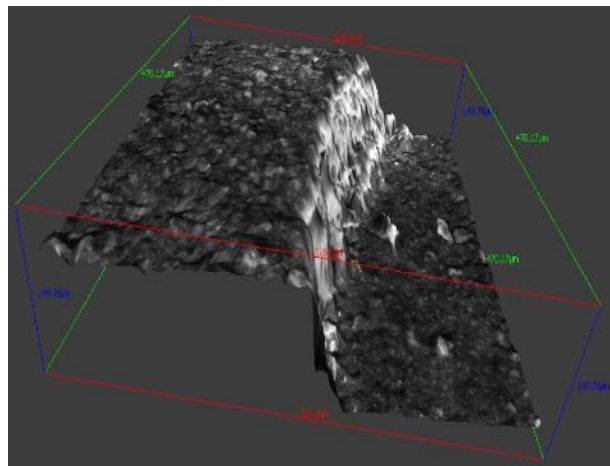
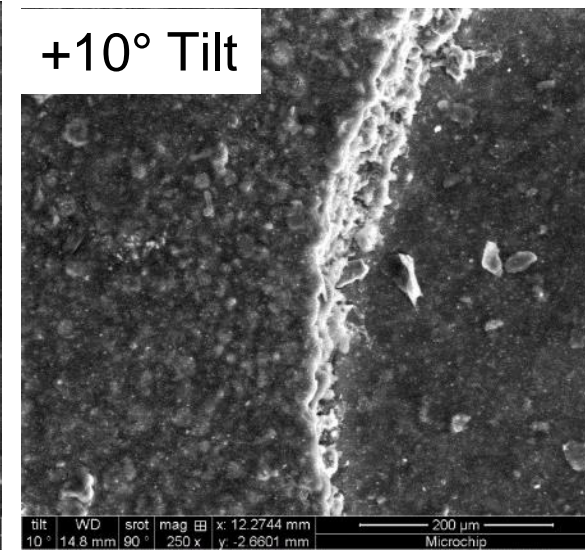
-10° Tilt



0° Tilt



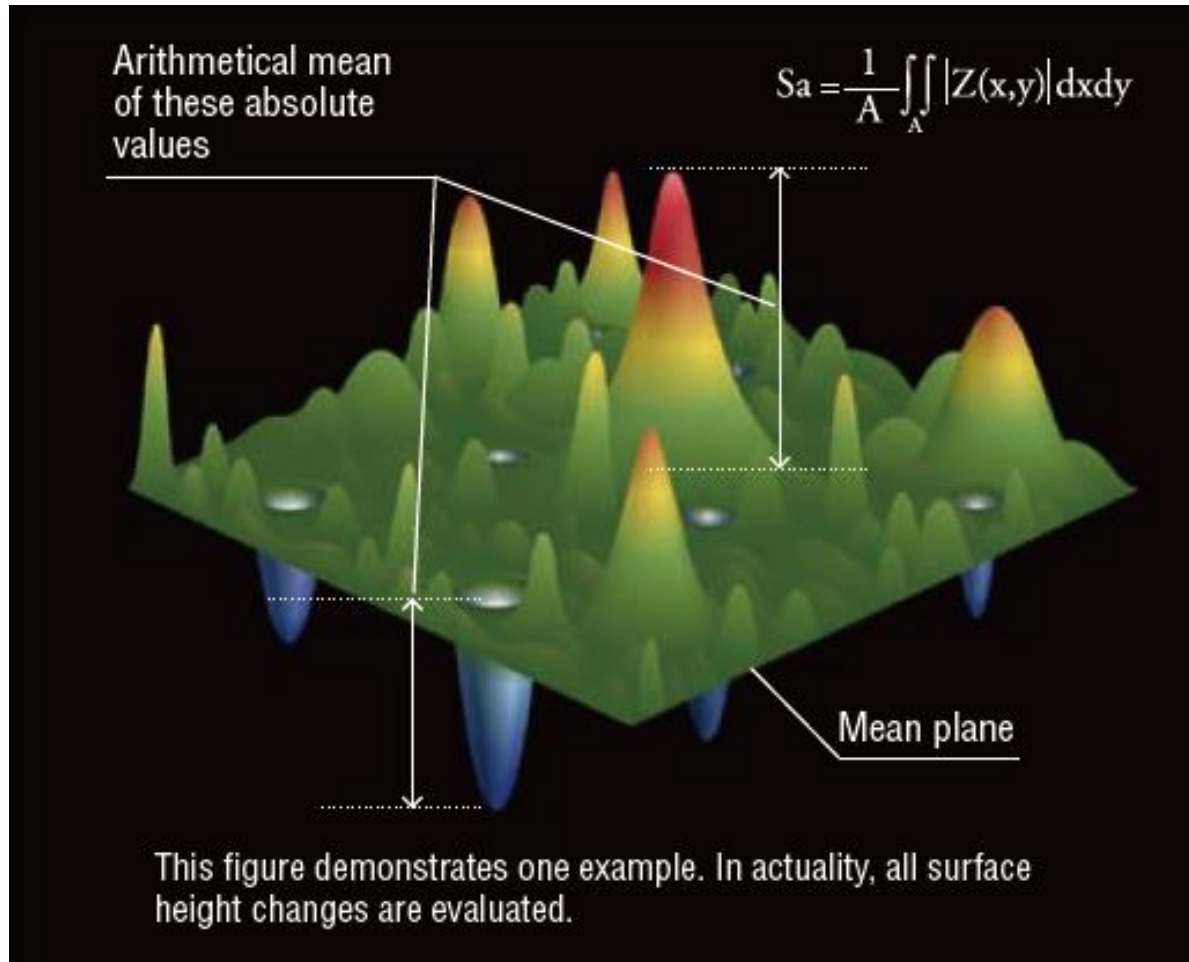
+10° Tilt



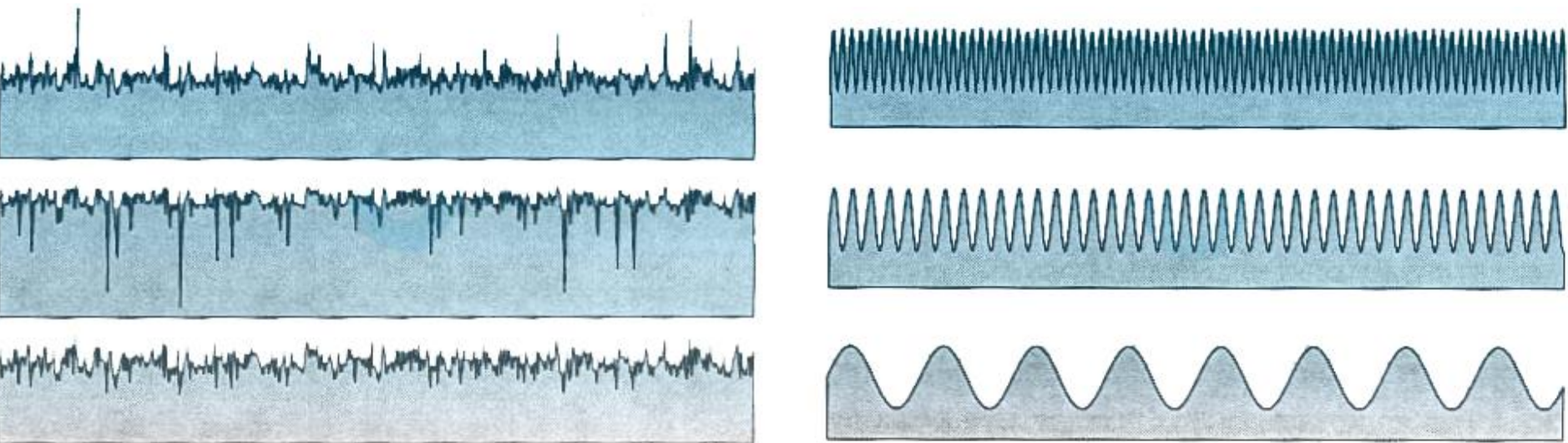
3D surface reconstruction from only 3 images while maintaining the actual texture of the dimples

Surface Parameters for quantification

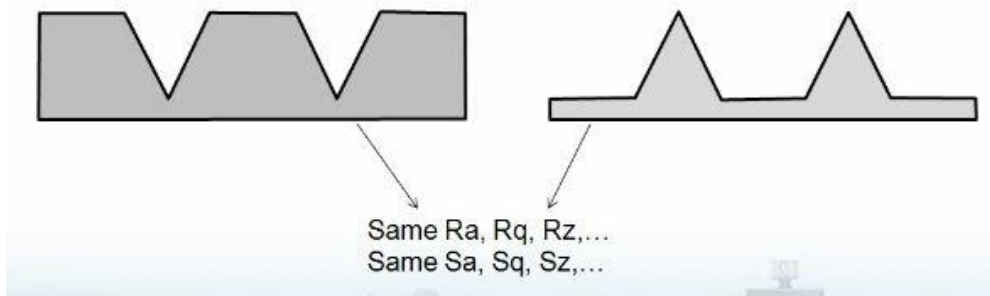
Height Sa (arithmetical mean height)



Surface Parameters for quantification



Some parameters have to be used that concerns heights and peaks/ volume analysis

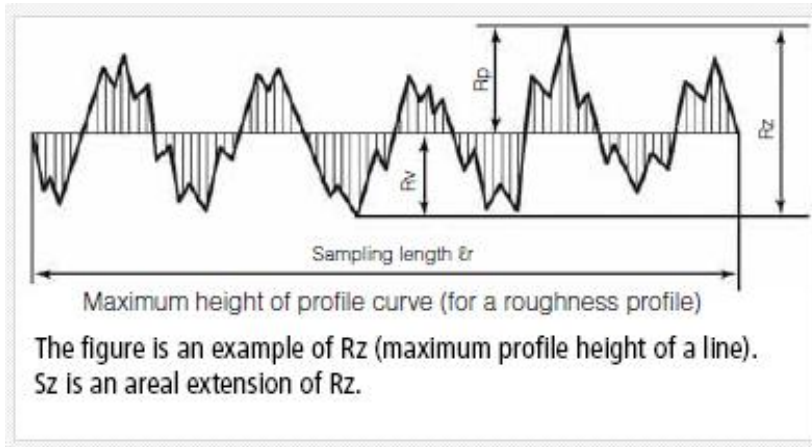


Surface Parameters for quantification

Height Sz (Maximum height)

sum of the largest peak height value and the largest pit depth value within the defined area

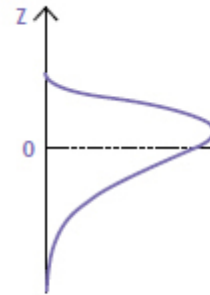
$$S_z = S_p + S_v$$



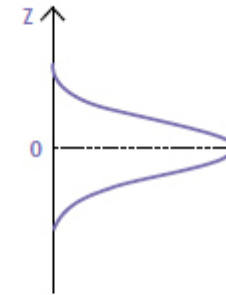
Ssk (Skewness)

represent the degree of bias of the roughness shape (asperity)

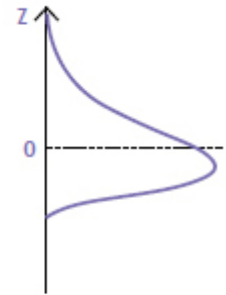
$$S_{sk} = \frac{1}{s_q^3} \left[\frac{1}{A} \iint_A Z^3(x,y) dx dy \right]$$



Ssk < 0



Ssk = 0



Ssk > 0

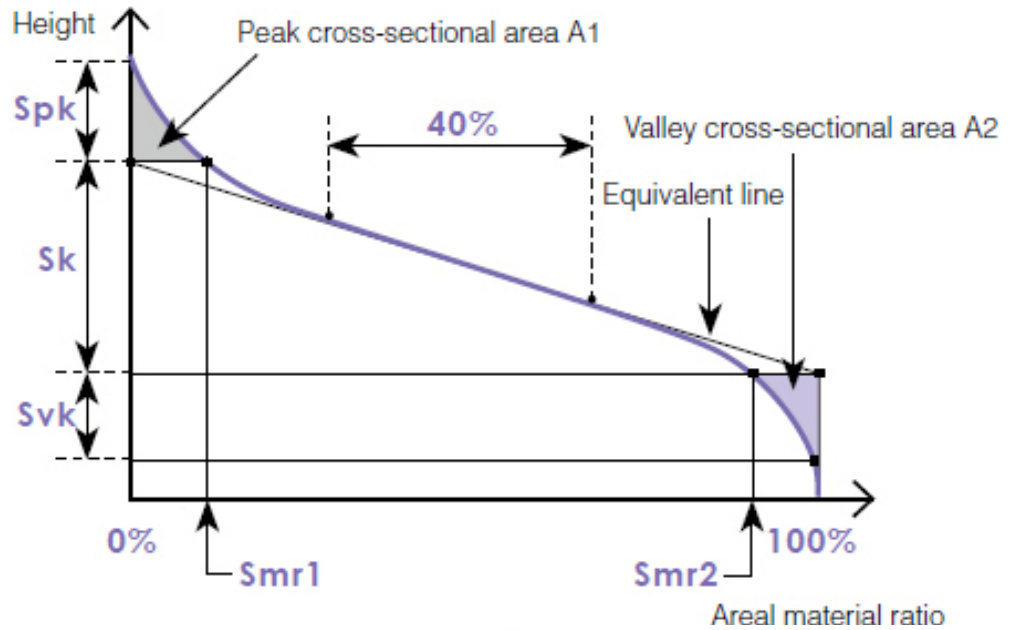
Ssk < 0: Height distribution is skewed above the mean plane.

Ssk = 0: Height distribution (peaks and pits) is symmetrical around the mean plane.

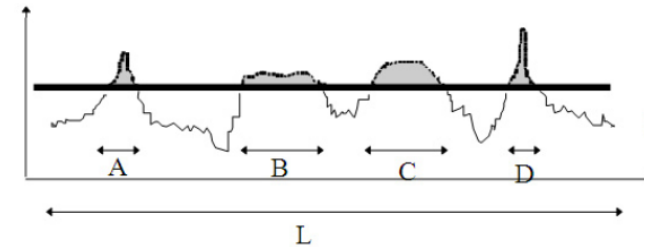
Ssk > 0: Height distribution is skewed below the mean plane.

Surface Parameters for quantification

The **areal material ratio curve** of an area is a curve representing heights at which the areal material ratio changes from 0% to 100%



$$\text{Aerial material ratio} = (A+B+C+D)/L$$



- Functional S_k (Core roughness depth)
- S_{pk} (Reduced peak height)
- S_{vk} (reduced dale height (reduced valley depth))

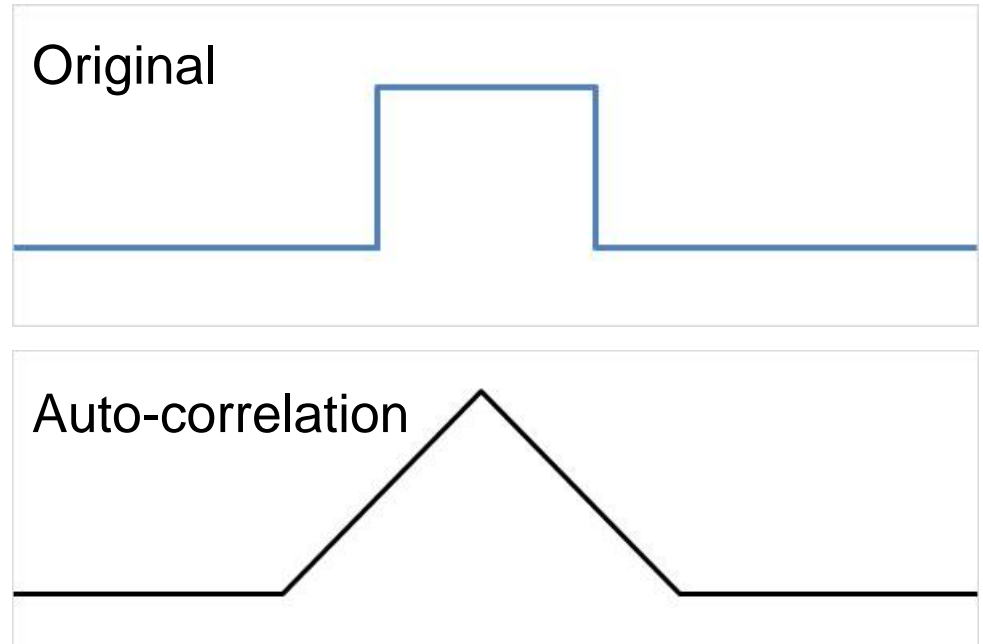
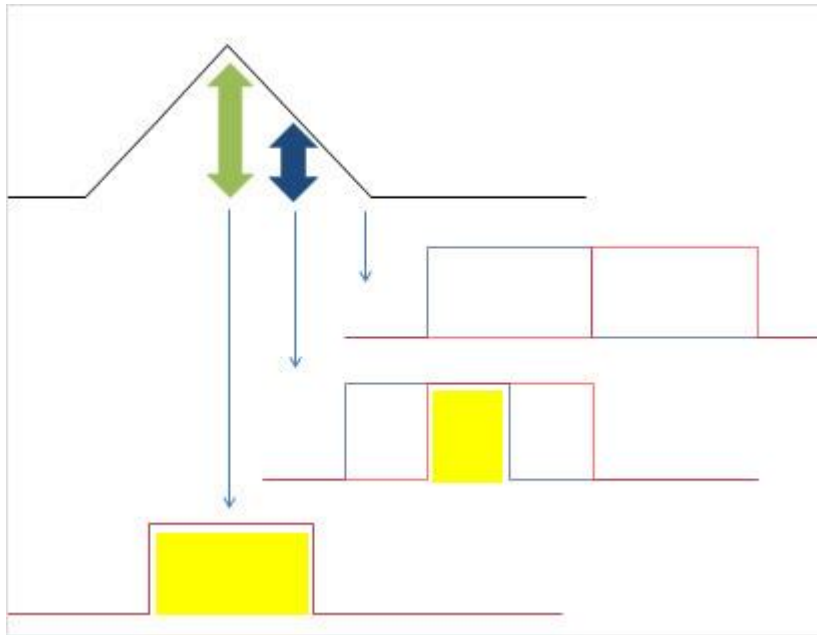
Surface Parameters for quantification

Spatial Sal (Auto-correlation length)

Represents horizontal distance in the direction in which the auto-correlation function decays to the value[s] (0.2 by default) the fastest.

$$f_{ACF}(t_x, t_y) = \frac{\iint_A z(x, y)z(x-t_x, y-t_y)dx dy}{\iint_A z(x, y)z(x, y)dx dy}$$

In image processing, an auto-correlation function is a measure of the matching ratio between an image rendered in different coordinates and the original image

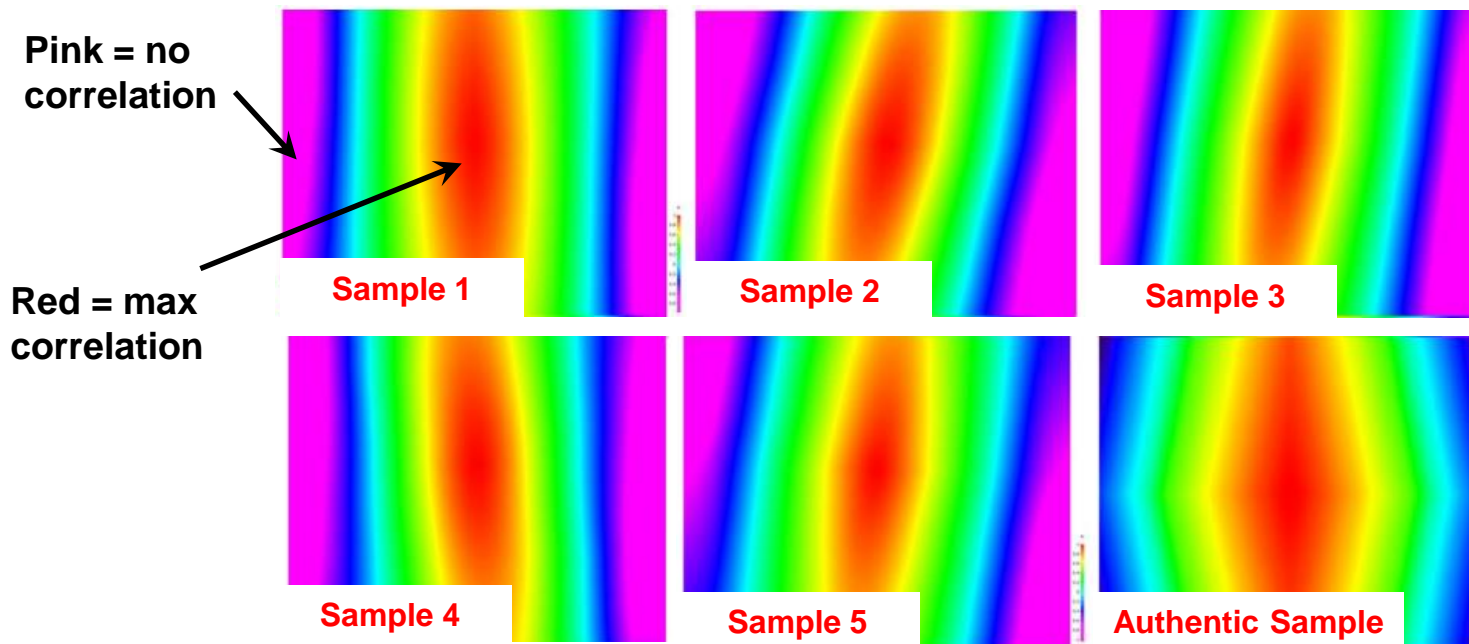


When the difference is small, the overlapping area is large, as is the auto-correlation value.
When the difference is large, the overlapping area is small, as is the auto-correlation value

$$R(t_i, t_j) = \frac{1}{(M-i)(N-j)} \sum_{l=1}^{N-j} \sum_{k=l}^{M-i} Z(x_k, y_l) Z(x_{k+i}, y_{l+j})$$

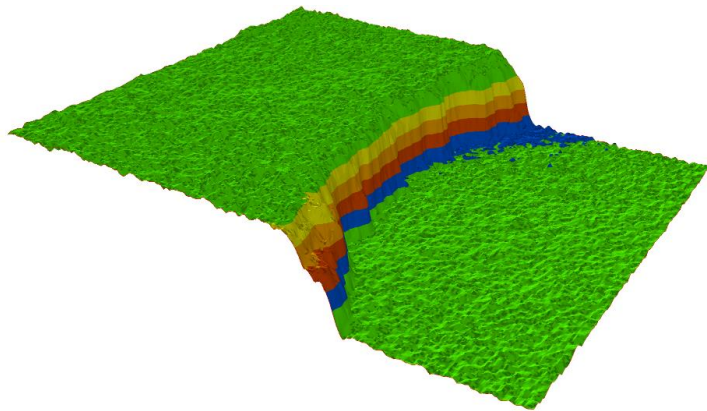
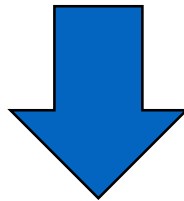
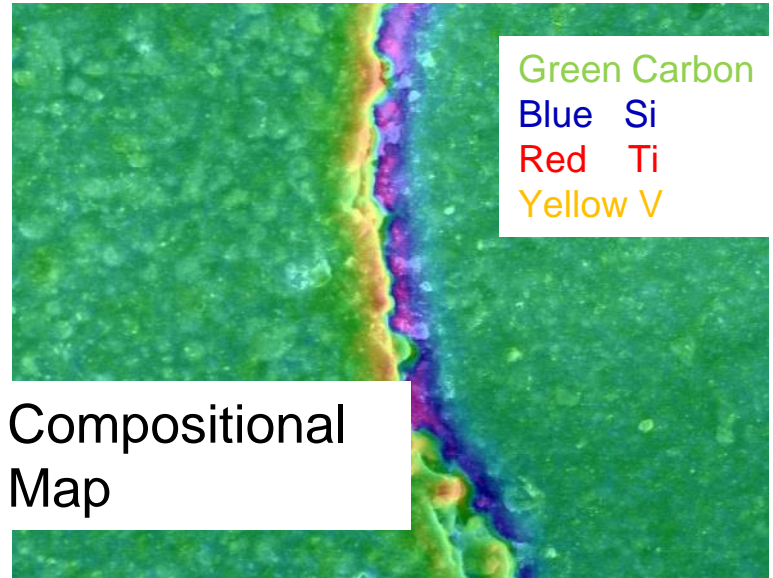
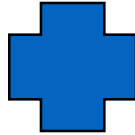
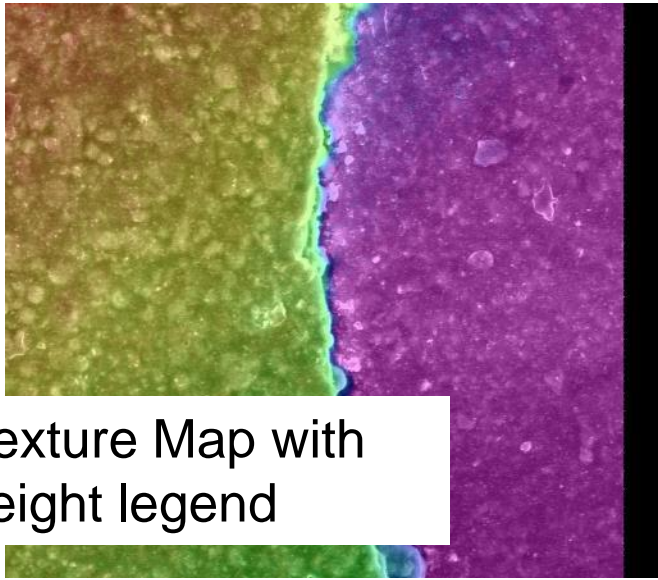
$i = 0, 1, \dots, m < M; j = 0, 1, \dots, n < N; t_i = i \cdot \Delta x; t_j = j \cdot \Delta y$

Areal Autocorrelation Function (AACF)



Surface Parameters for quantification

Functional	S _{mr(c)} Areal material (bearing area) ratio
	S _{mc(mr)} Inverse areal material ratio
	S _k (Core roughness depth)
	S _{pk} (Reduced peak height)
	S _{vk} (reduced dale height (reduced valley depth))
	S _{mr} (Peak material portion)
	S _{mr2} (Valley material portion)
	S _{xp} (Peak extreme height)
Functional volume	V _{vv} (Dale void volume)
	V _{vc} (Core void volume)
	V _{mp} (Peak material volume)
	V _{mc} (Core material volume)
Feature	S _{pd} (Density of peaks)
	S _{pc} (Arithmetic mean peak curvature)
	S _{10z} / S _{5p} / S _{5v} / S _{da(c)} / S _{ha(c)} / S _{dv(c)} / S _{hv(c)}



Compositional Map on the 3D Dimple, green represents Carbon and blue, red and yellow are Si, Ti and V respectively

Tools for Visual Inspection

OBSERVATION	INSTRUMENT	OTHER COMMON METHODS
Residue on leads	SEM/X-ray	X-ray Fluorescence (XRF), Optical Microscopy
Sanding marks	SEM/EDS	Optical Microscopy, XRF
Coated/filled dimples	SEM/X-ray	LSM, Optical profilometry
Dimple depth variation	SEM/X-ray	LSM, Optical Profilometry
Incorrect lead plating (Sn vs. Sn/Pb)	SEM/EDS	XRF
No exposed lead base metal	SEM	XRF, Optical Methods
Bent leads	SEM/X-ray	Optical Methods
Metal shavings and/or tin whiskers on leads	SEM	SEM, Optical Microscopy
Different die sizes	X-ray	Decapsulation, Scanning Acoustic Microscopy (SAM)
Different lead frames	X-ray	Decapsulation
Wire bond pattern variations	X-ray	Decapsulation, SAM
No barrier metal under pure Sn lead finish	SEM	XRF, Optical Microscopy
Blacktopping (top and bottom surfaces)	SEM/X-ray	Destructive Liquid Testing

- <https://www.microscopyu.com/>
- ISTFA paper: Advanced Physical Inspection Methods for Counterfeit IC Detection